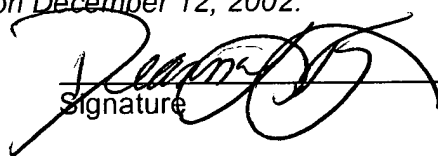




PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner of Patents and Trademarks, Washington, D.C. 20231 on December 12, 2002.

  
Signature

8/A Andell  
3-13-03  
FLW

Applicant: Isik C. Kizilyalli, et al.  
Application No.: 09/882,367  
Filed: June 15, 2001  
Title: CMOS DEVICE FABRICATION UTILIZING  
SELECTIVE LASER ANNEAL TO FORM RAISED  
SOURCE/DRAIN AREAS

Grp./Div.: 2822  
Examiner: Maria F. Guerrero

Docket No.: 41277/MJM/A717

RESPONSE TO OFFICE ACTION DATED SEPTEMBER 13, 2002

Assistant Commissioner for Patents  
Washington, D.C. 20231

Post Office Box 7068  
Pasadena, CA 91109-7068  
December 12, 2002

Commissioner:

In response to the Office action dated September 13, 2002, please amend the above-identified application as follows and re-examine and reconsider the application in view of the amendments and remarks provided.

AMENDMENTS

In the Claims:

Please cancel claims 2,14,18 and 21. Add new claim 27. Please amend claims 1,13,17,20, 24 and 26 as indicated in the attached Version With Markings to Show Changes Made. The complete set of pending claims, in amended version, is as follows:

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